

# Radiation damage in Si-based sensors - from “microscopic” reasons to “macroscopic” consequences for detector performance

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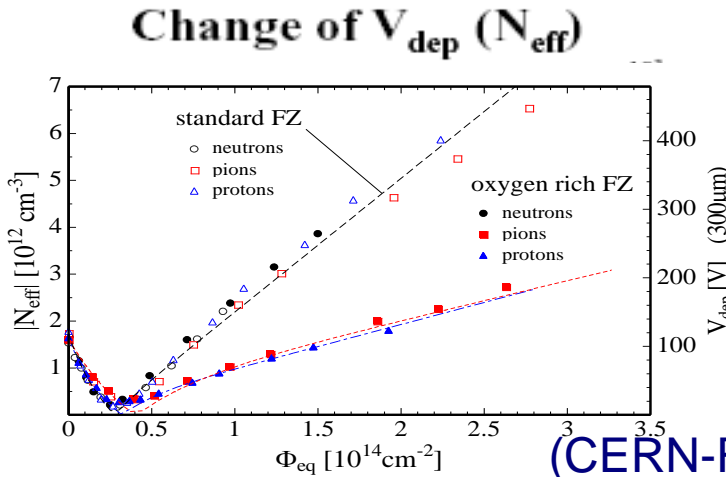
Work performed in the framework of CERN-RD50 Collaboration ( <http://rd50.web.cern.ch/rd50/>)

# Motivation

a) bulk radiation damage - resulting from the non-ionizing energy loss (as e.g. LHC and SLHC)

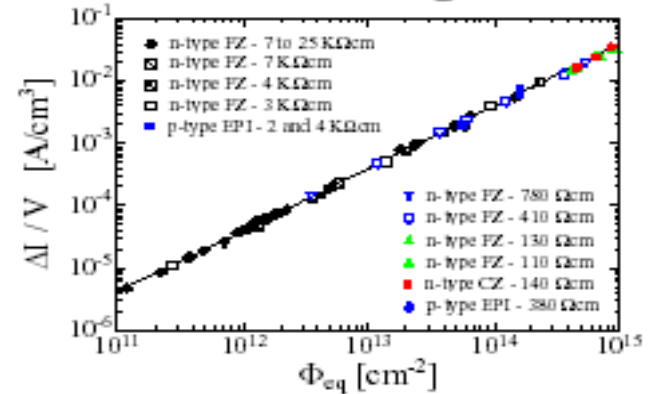
## Radiation Damage – Macroscopic Effects

Irradiation



(CERN-RD48)

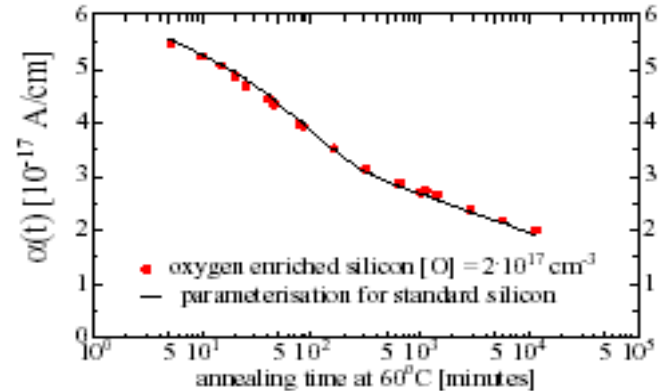
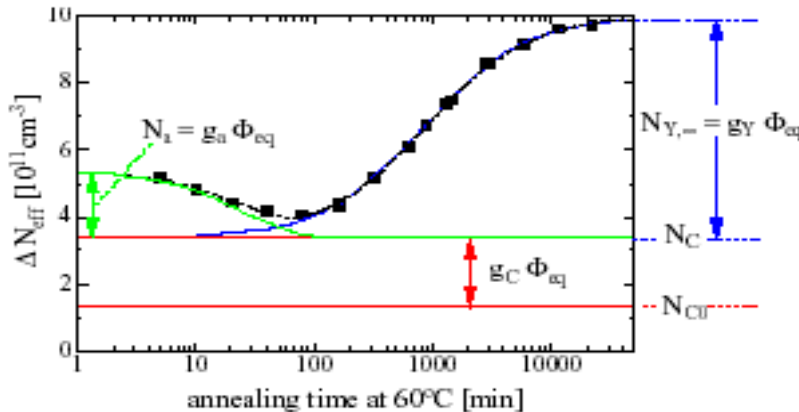
## Increase of leakage current



Nucl. Inst. Meth. A 466, 308-326, (2001)

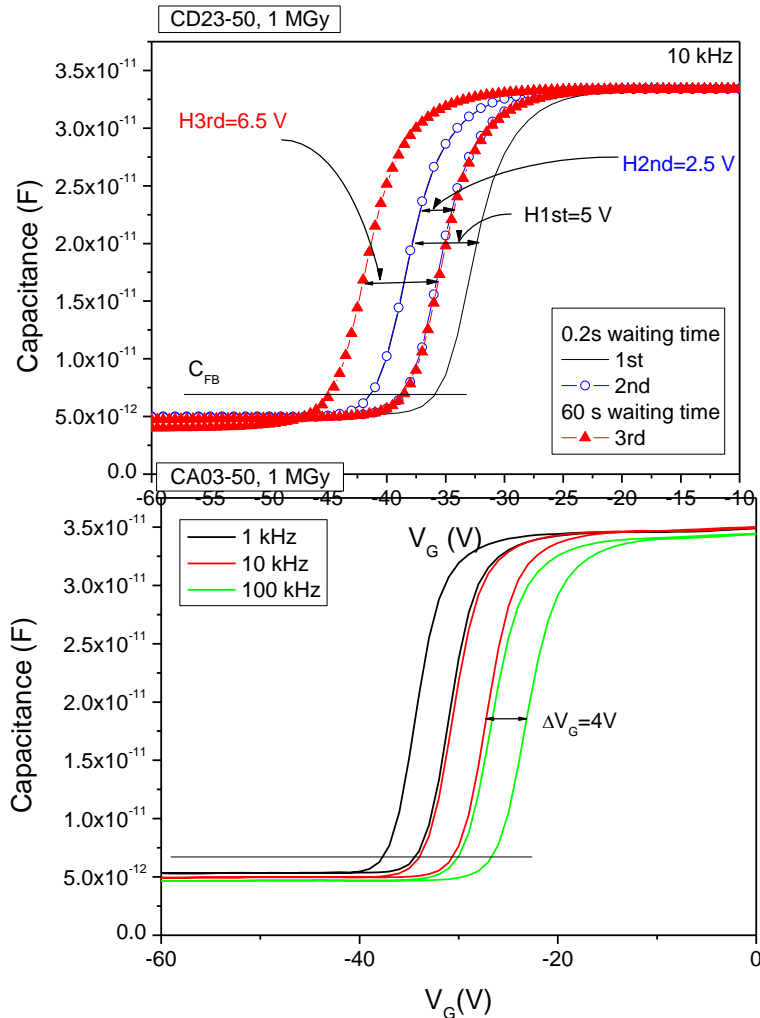
Annealing

(e.g. at 60°C)



**“Defect engineering” needed for SLHC application in the tracking area to improve the detectors radiation tolerance**

**b) Surface and interface related effects** - caused by ionization in environments with high X-ray doses (as e.g. in XFEL: Doses of up to 1GGy in 3 years of operation, up to  $10^5$  12 keV photons per pixel of  $200 \mu\text{m} \times 200 \mu\text{m}$ ).



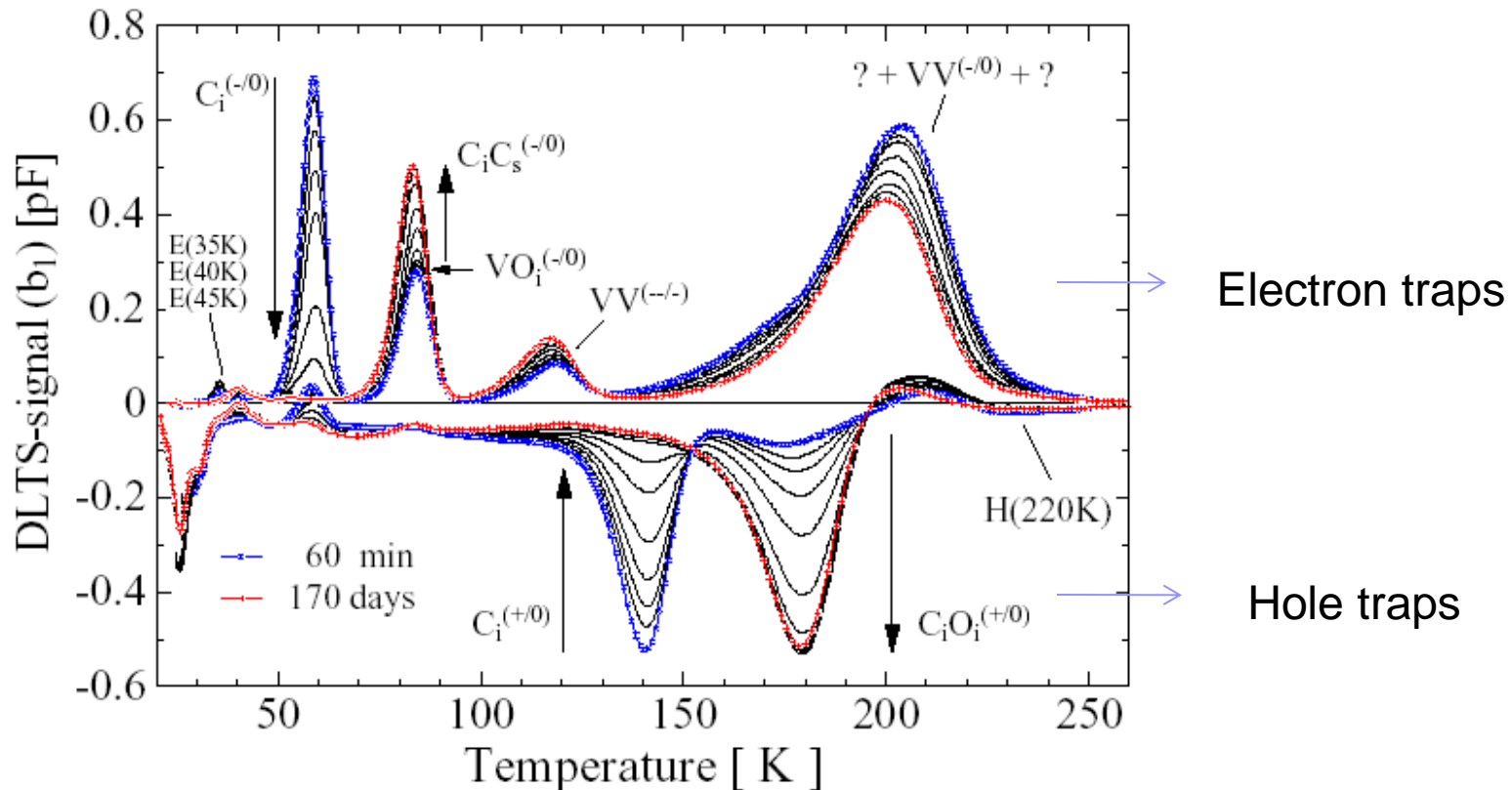
## MOS with high resistivity Si (for XFEL)

- Irreproducibility of C/G-V curves ( $V_{FB}$  depending on frequency and on bias history)
- Strong annealing effects at room temperature
- No existing data related to electrical parameters of interface states

***Defect investigations needed to understand and to predict the performance of segmented Si sensors as a function of the X-ray dose***

## a) bulk radiation damage

starting point in our investigations on p<sup>+</sup>-n Si diodes – *typical DLTS spectra*

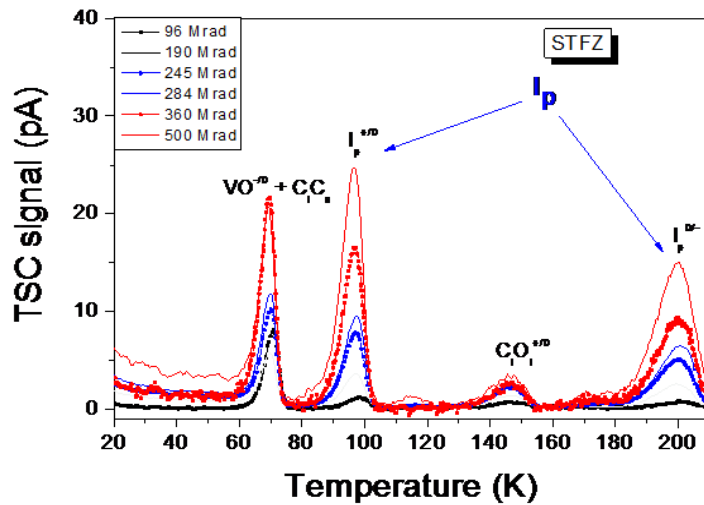


Phys. Rev. B **13**, 2653 , (1976); Radiat. Eff. **29**, 7, (1976); J. Appl. Phys. **79**, 3906, (1996); Nucl.Instrum. Methods Phys. Res. A **388**, 335 , (1997); M. Moll, Ph.D. thesis, DESY thesis 1999-040, ISSN 1435-8085, 1999

None of these defects explain the macroscopic behaviour of the irradiated diodes

# I) Search for still undetected defects responsible for the radiation damage, as seen at operating temperatures

- Point defects (after gamma and low energy electron irradiation)



## $I_p$ center in STFZ (O lean material)

- **deep acceptor (-/0)**
  - $E_a = E_c - 0.545 \text{ eV}$
  - $\sigma_n = (1.7 \pm 0.2) \times 10^{-15} \text{ cm}^2$ ;
  - $\sigma_p = (9 \pm 1) \times 10^{-14} \text{ cm}^2$
- ~ 90% occupied with (-) at RT

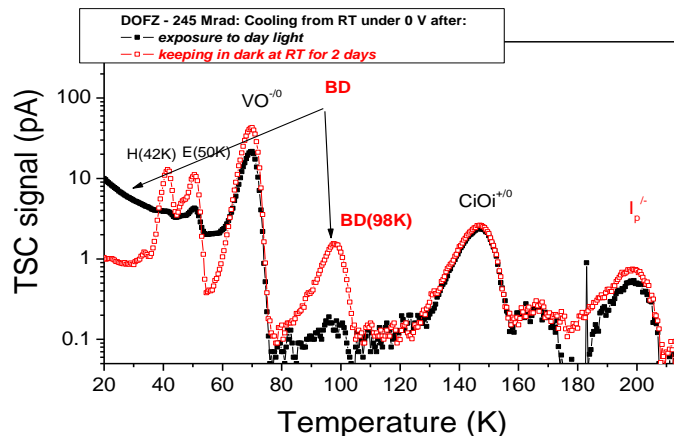
## BD center –generated in DOFZ (O rich material)

- **shallow donor (+ at RT)**

$$E_i^{BD(98K)} = E_c - 0.225 \text{ eV } (0/++);$$

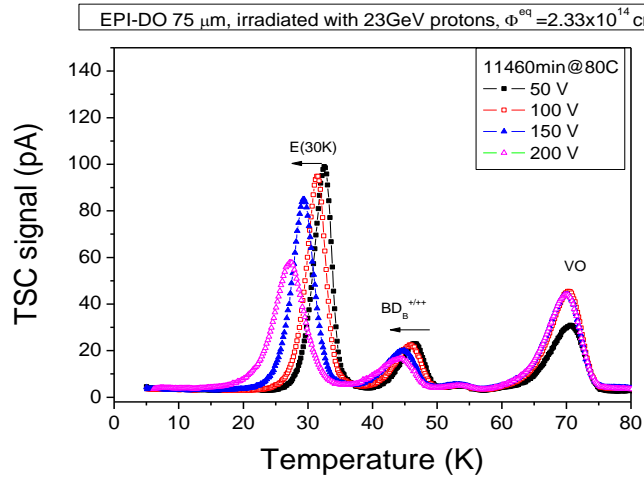
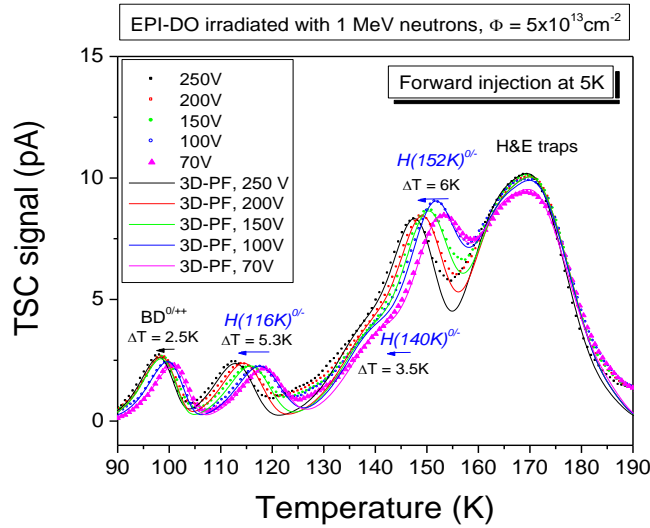
$$E_i^{BD(50K)} = E_c - 0.15 \text{ eV } (+/++)$$

**Overcompensates the effect of  $I_p$  acceptors!**



- I. Pintilie et al, APPL. PHYS. LETT. 81, 165-167, 2002
- I. Pintilie et al, APPL. PHYS. LETT 82, 2169 (2003);
- I. Pintilie et al, Nucl. Inst. Meth. A 514, 18-24, (2003)

Extended defects (clusters), responsible for hadron damage



Cluster related centers

$$E_i^{116K} = E_v + 0.33\text{eV}$$

$$\sigma_p^{116K} = 4 \cdot 10^{-14} \text{ cm}^2$$

$$E_i^{140K} = E_v + 0.36\text{eV}$$

$$\sigma_p^{140K} = 2.5 \cdot 10^{-15} \text{ cm}^2$$

$$E_i^{152K} = E_v + 0.42\text{eV}$$

$$\sigma_p^{152K} = 2.3 \cdot 10^{-14} \text{ cm}^2$$

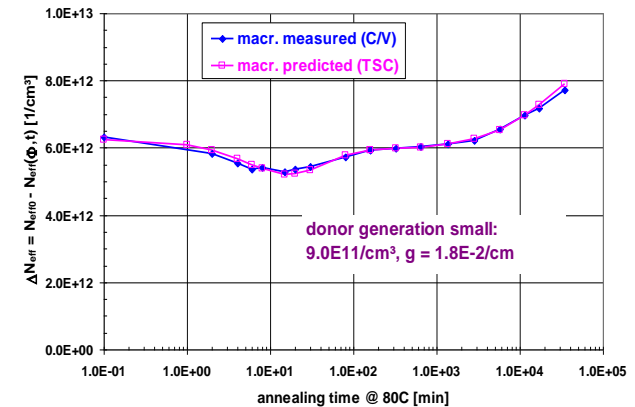
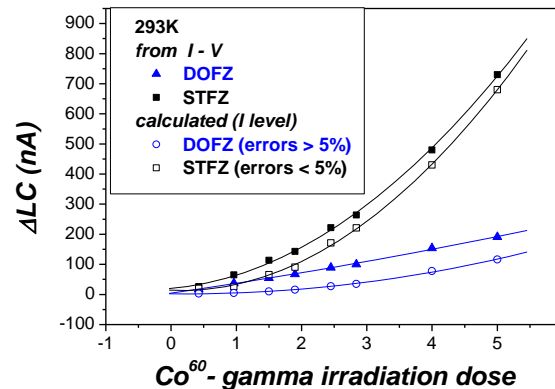
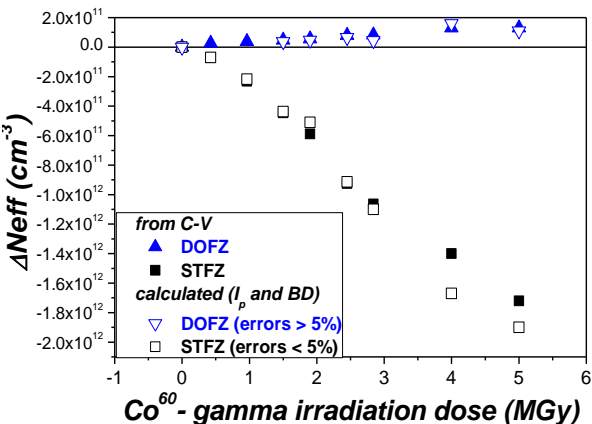
$$E_i^{30K} = E_c - 0.1\text{eV}$$

$$\sigma_n^{30K} = 2.3 \cdot 10^{-14} \text{ cm}^2$$

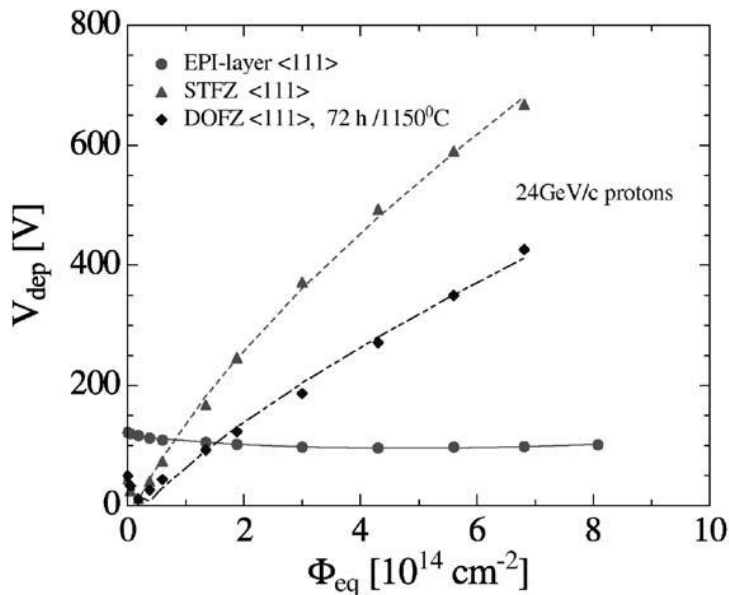
enhanced generation after irradiation with charged hadrons

II) Bridge the gap between the defect analyses and device performances as a crucial step for further device developments

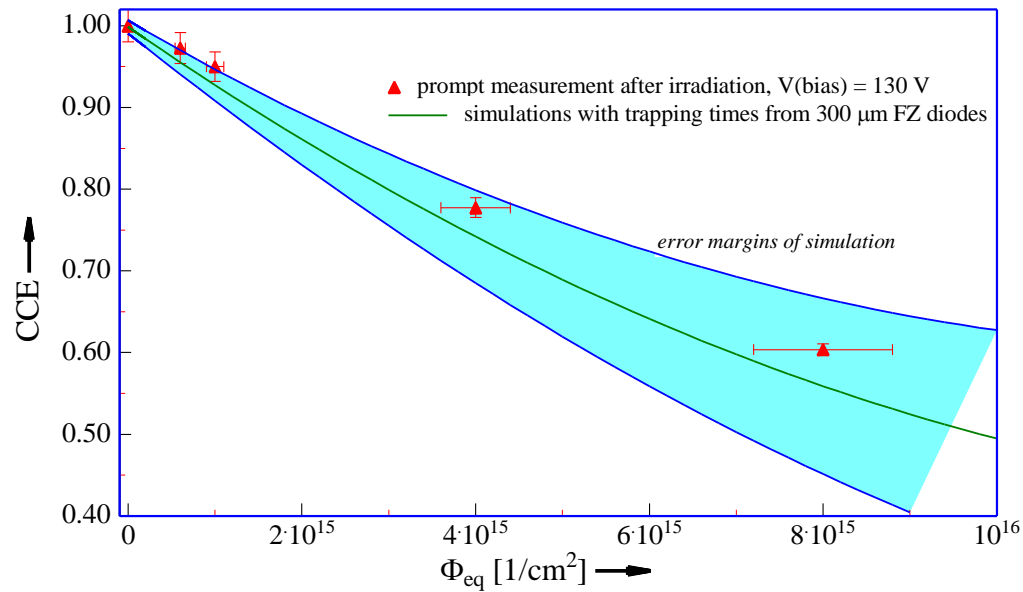
75 μm EPI-DO, 1 MeV-eq. n-irradiation,  $\Phi_{eq} = 5.0\text{E}13/\text{cm}^2$



# Superior radiation tolerance of thin epi-silicon detectors



Fluence dependence of  $V_{dep}$  after 24 GeV/c proton irradiation for Epi (50  $\mu\text{m}$ , 50  $\Omega\text{cm}$ ), STFZ (300  $\mu\text{m}$ , 2-5k $\Omega\text{cm}$ ) and DOFZ silicon (300  $\mu\text{m}$ , 2-5k $\Omega\text{cm}$ )



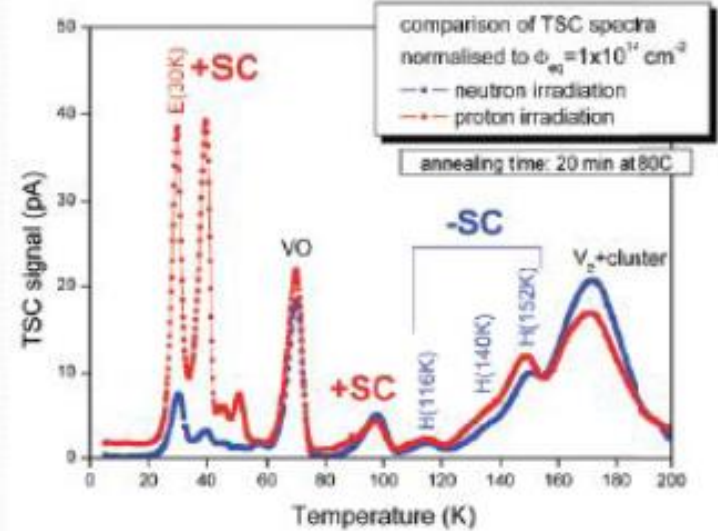
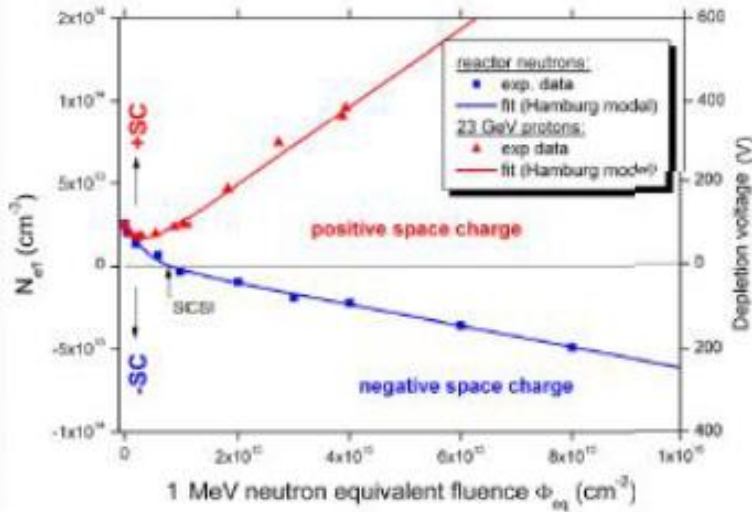
Charge collection efficiency after reactor-neutron irradiation in Epi/Cz-silicon (50  $\mu\text{m}$ , 50  $\Omega\text{cm}$ )

## Epi-Si:

- no type inversion for protons, small increase of positive space charge
- Radiation hardness up to  $8 \cdot 10^{15} \text{ n/cm}^2$  demonstrated
- CCE = 60% sufficient for requested S/N – ratio in SLHC applications
- $N_{eff}$  - Dependence on particle type (protons vs. neutrons) - *Violation of NIEL (Non Ionizing Energy Loss) Hypothesis!*

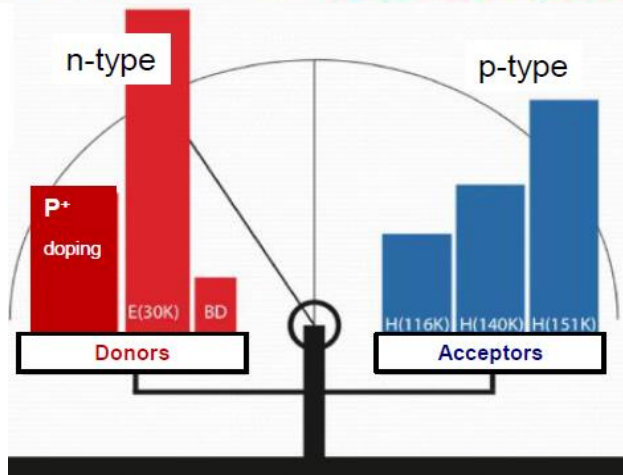


**$N_{eff}$**  - Dependence on particle type (protons vs. neutrons) - *Violation of NIEL (Non Ionizing Energy Loss) Hypothesis!*

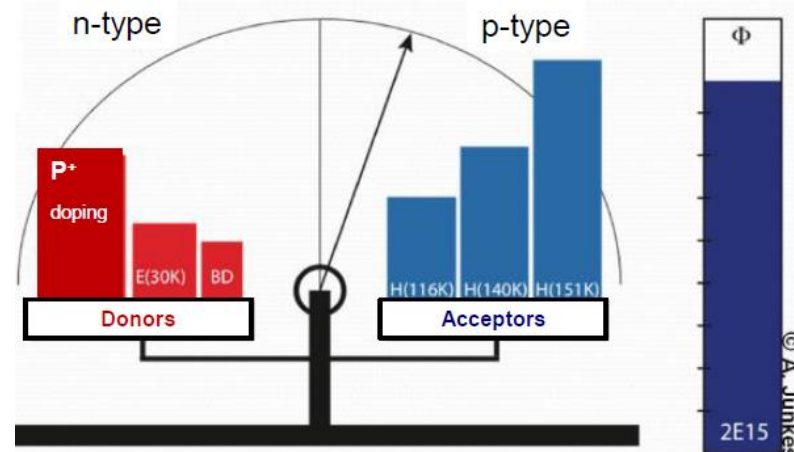


**Epitaxial silicon (EPI-DO, 72 $\mu$ m, 170 $\Omega$ cm, diodes)**

irradiated with **23 GeV protons**



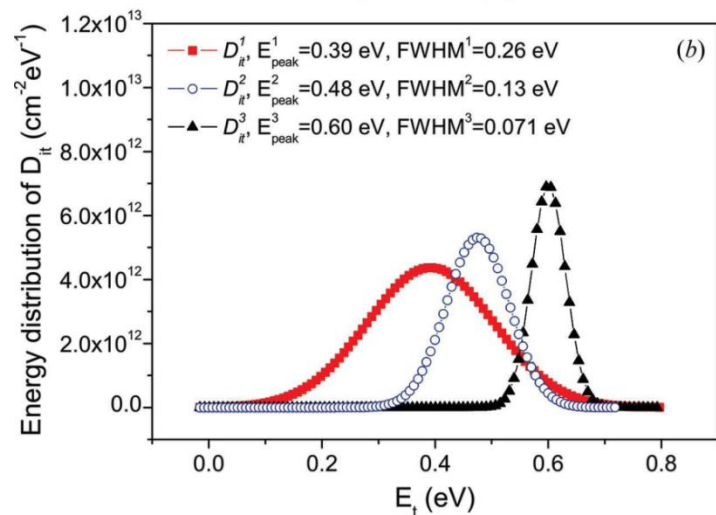
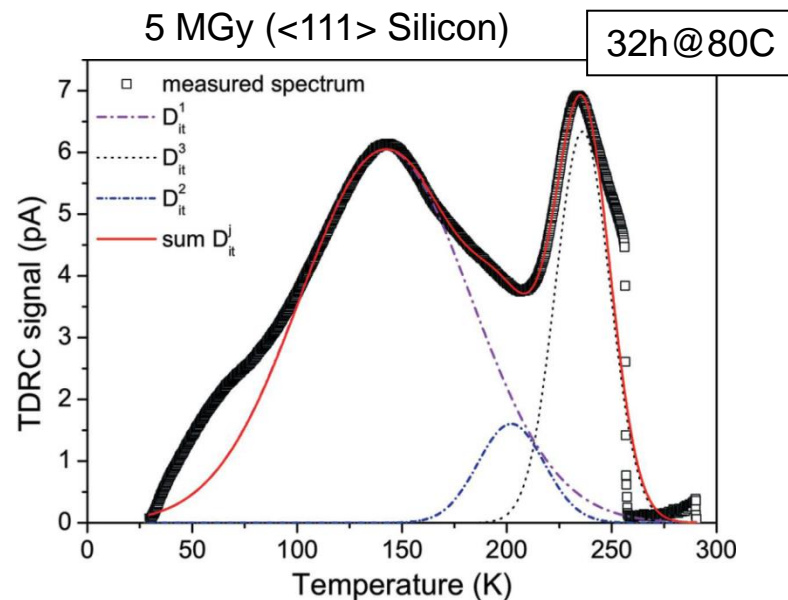
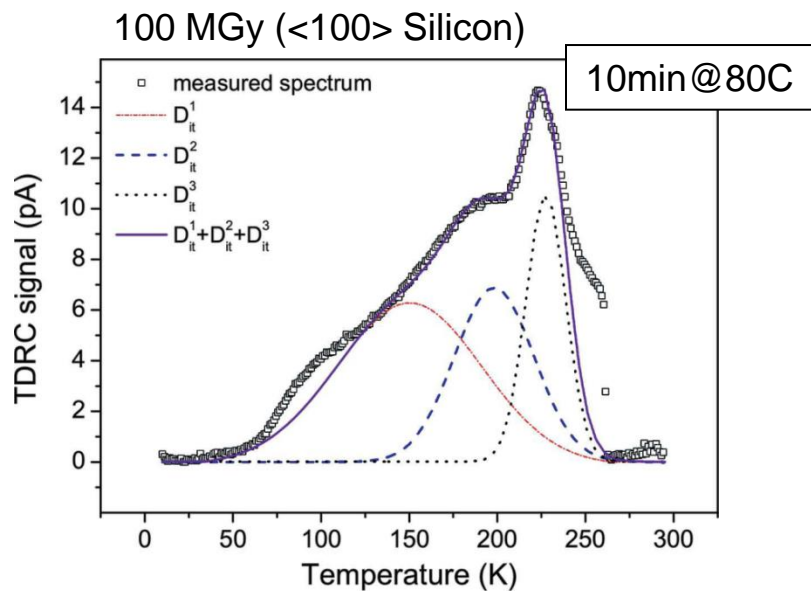
irradiated with **reactor neutrons**





## b) Surface and interface related effects

### I) Detection and characterization of Interface states in MOS structures with high resistivity Si (for XFEL)

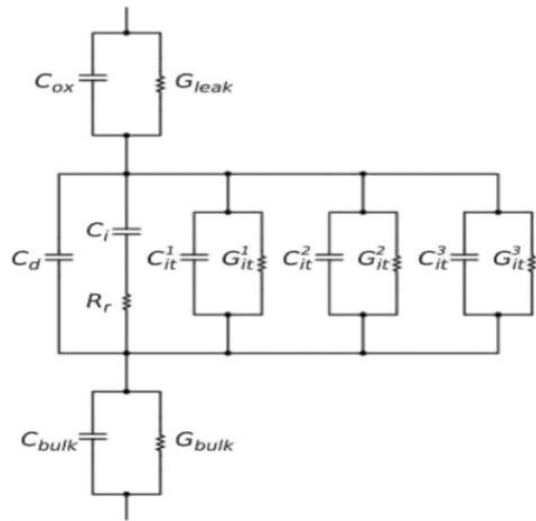


J. Synchrotron Rad. (2012). 19, 340–346

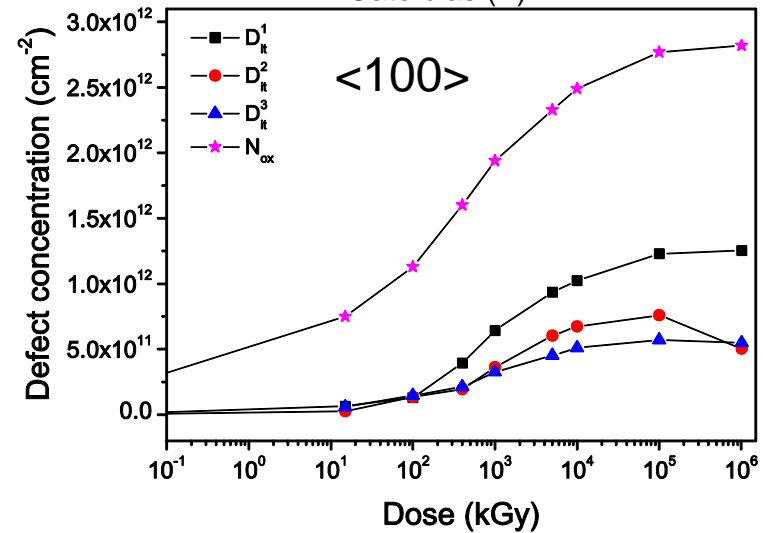
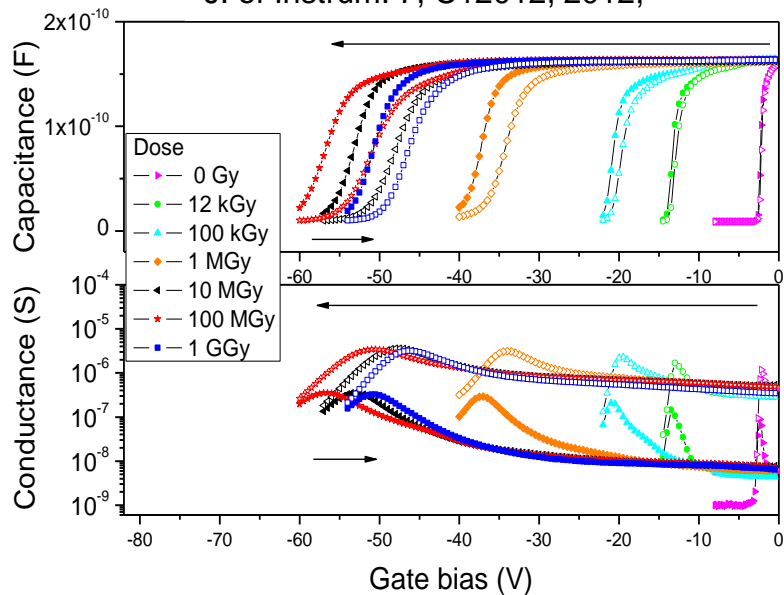
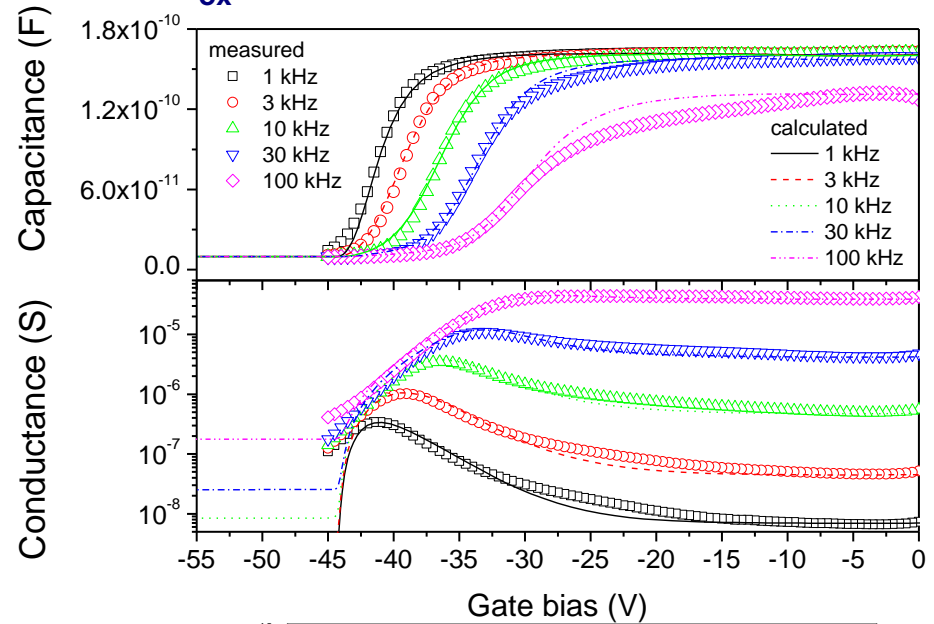
	$D_{it}^1$	$D_{it}^2$	$D_{it}^3$
$\sigma$ [ $\text{cm}^2$ ]	$1.2 \times 10^{-15}$	$5 \times 10^{-17}$	$1.0 \times 10^{-15}$
peak energy [eV]	0.39	0.48	0.60
FWHM [eV]	0.26	0.13	0.071

## II) Bridge the gap between the defect analyses and device characteristics

### Calculation of C/G-V curves and determination of $N_{ox}$



J. Synchrotron Rad. (2012). 19, 340–346;  
J. of Instrum. 7, C12012, 2012;



For <111> material the  $D_{it}$  and  $N_{ox}$  are ~ 20-30 % higher

# Conclusions

- Direct correlation between defect investigations and device properties can be achieved! Moreover, when electrical characteristics of the defects are known then models predicting the device performance in different operational scenarios can be developed
- Atomic and electronic point defects – dependent on the material  $\Rightarrow$  defect engineering does work
- Cluster related defects – independent on the material  $\Rightarrow$  Possibility of compensation with point defects via defect engineering
- Still missing the identification of the chemical nature of the defects that deteriorates the device characteristics

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